

STRUCTURAL AND ELECTRICAL CONDUCTIVITY MEASUREMENT OF  
ZINC OXIDE THIN FILM PREPARED BY SOL-GEL DIP COATING METHOD

PEH LY TAT

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To my beloved family members and  
especially Mrs. Sheley Wang who always offered me the mighty support and love  
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## ABSTRACT

Zinc oxide (ZnO) exhibits a hexagonal wurtzitic structure with a wide direct energy band gap of 3.37 eV. Furthermore, the ZnO thin films have low resistivity and high transparency in visible region and thus can be used as the fundamental layer in the fabrication of optoelectronic devices and as the transparent electrodes in solar cell panel. Undoped ZnO thin films were deposited onto corning glass substrates via the sol-gel dip coating method with annealing temperature and solution concentration being varied. The films were prepared under the annealing temperatures and solution concentrations ranging from 350 to 550 °C and 0.10 M to 0.30 M respectively. The effects of lowering the annealing temperature and solution concentration onto the characteristics of ZnO films were studied. The prepared sol-gel ZnO films can be used as a part of fundamental platform for the synthesis of novel ZnO nanostructures such as nanorods (1D) and nanowires (2D). The starting material in the form of zinc acetate dehydrates was dissolved into a mixing solution consisting of isopropanol and diethanolamine which acts as the solvent and stabilizer respectively. The thickness of the films has been measured by a surface profilometer. The structural properties of sol-gel ZnO films were characterized by X-Ray diffractometer (XRD) and atomic force microscope (AFM). Meanwhile, the film conductivity level was determined by Van der Pauw resistivity measurement method. The XRD spectra revealed that the prepared sol-gel ZnO films were polycrystalline with the hexagonal wurtzite structure and had the preferential growth along (002) c-axis orientation. The ZnO films prepared at 0.30 M concentration and annealed at 450 °C showed the highest crystallinity among all the samples. The grain size and the root mean square roughness of the ZnO films increased with the increase of annealing temperature and solution concentration. Furthermore, the biggest grain size of 66.60 nm was observed for ZnO films prepared with 0.30 M concentration and annealed at 550 °C. The thickness of ZnO films annealed at 450 °C increases from 63 to 260 nm as the solution concentration increases from 0.10 to 0.30 M. The ZnO films prepared with 0.30 M concentration and annealed at 350 °C showed the lowest conductivity value of  $2.49 \times 10^{-4}$  S/cm with the activation energy  $E_a = 27$  meV. Meanwhile, the highest film conductivity level was observed for the ZnO film prepared at 0.30 M concentration and annealed at 450 °C with value of  $1.29 \times 10^{-2}$  S/cm with  $E_a = 95$  meV.

## ABSTRAK

Zink oksida (ZnO) menyerupai struktur suatu wurtzite heksagon berserta dengan sela jalur tenaga terus 3.37 eV. Selanjutnya, sputer tipis ZnO mempunyai kerintangan elektrik yang rendah dan ketelusan lutsinar yang tinggi yang membolehkannya digunakan sebagai lapisan asas peranti optoelektronik dan elektrod lutsinar pada panel sel suria. Sputer tipis ZnO yang belum didopkan dimendap pada substrat korning kaca menggunakan kaedah penyaduran secara pencelupan sol-gel. Sputer tipis ZnO disepuh lindap pada suhu penyepuhlindapan dan kepekatan larutan berjulat masing-masing daripada 350 °C hingga 550 °C dan 0.10 M hingga 0.30 M. Kesan suhu penyepuhlindapan dan kepekatan larutan yang rendah terhadap sifat sputer tips ZnO telah dikaji. Sputer tipis ZnO yang telah dimendap melalui kaedah pencelupan sol-gel sesuai digunakan sebagai lapisan asas bagi sintesis struktur nano ZnO novel seperti nanorod (1D) dan nanowayar (2D). Serbuk kering zink acetate melarut dalam larutan yang mengandungi pelarut isopropanol dan diethanolamine. Ketebalan sputer tipis ZnO diukur dengan menggunakan profilometer permukaan. Manakala, sifat struktur dikaji dengan menggunakan teknik analisis seperti difraktometer sinaran-X (XRD) dan mikroskop daya atom (AFM). Sifat kekonduksian elektrik diukur dengan menggunakan kaedah Van der Pauw. Spektrum XRD menunjukkan sputer tipis ZnO mempunyai polihabluran yang berstruktur heksagonal berserta dengan (002) paksi-c sebagai arah pertumbuhan utama struktur hablur. Sputer tipis ZnO yang disediakan pada kepekatan 0.30 M dan disepuh lindap pada suhu 450 °C menunjukkan penghabluran terbaik di kalangan sampel. Saiz hablur dan morfologi sputer tipis ZnO didapati meningkat dengan kenaikan suhu penyepuhlindapan dan kepekatan larutan. Saiz hablur yang terbesar ialah 66.60 nm diperolehi pada sputer tipis ZnO yang disediakan dengan kepekatan 0.30 M dan suhu penyepuhlindapan 550 °C. Ketebalan sputer tipis ZnO yang disepuh lindap pada suhu 450 °C didapati meningkat daripada 63 hingga 260 nm apabila kepekatan larutan meningkat daripada 0.10 hingga 0.30 M. Sputer tipis ZnO yang disediakan pada kepekatan 0.30 M dan disepuh lindap pada suhu 350 °C menunjukkan tahap kekonduksian yang terendah iaitu  $2.49 \times 10^{-4}$  S/cm dengan tenaga pengaktifan  $E_a = 27$  meV. Manakala, sputer tipis ZnO yang disediakan pada kepekatan 0.30 M dan disepuh lindap pada suhu 450 °C didapati mempunyai tahap kekonduksian elektrik yang tertinggi iaitu  $1.29 \times 10^{-2}$  S/cm dengan  $E_a = 95$  meV.

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**LIST OF SYMBOLS AND ABBREVIATIONS**

ZnO	-	Zinc Oxide
ZnSe	-	Zinc Selenide
GaN	-	Gallium Nitrate
GaAs	-	Gallium Arsenide
InP	-	Indium Phosphide
CuO	-	Copper (II) Oxide
Zn	-	Zinc
Si	-	Silicon
Al	-	Aluminium
Ge	-	Germanium
P	-	Phosphorus
B	-	Boron
LED	-	Light Emitting Diode
XRD	-	X-ray Diffraction
AFM	-	Atomic Force Microscopy
EDX	-	Energy Dispersive Analysis of X-Ray
$E_g$	-	Energy Band Gap
$E_a$	-	Activation Energy
$n_0$	-	Concentration of Electron
$p_0$	-	Concentration of Holes
$n_i$	-	Equilibrium Concentration of electrons or holes in an intrinsic semiconductor
$a, c$	-	Lattice Constant
$d_{hkl}$	-	Lattice Interplanar Distance
$Zn_i$	-	Zinc Interstitials
$O_i$	-	Oxygen Interstitials
$V_{zn}$	-	Zinc Vacancies

DC	-	Direct Current
PLD	-	Pulse Laser Deposition
DEA	-	Diethanolamine
$\lambda$	-	Wavelength of Monochromatic X-ray Beam
$\theta$	-	Diffraction Bragg Angle
$\text{\AA}$	-	Angstrom = $10^{-10}$ m
D	-	Estimated Crystallite Size Derived From XRD
$\beta$	-	FWHM of $2\theta$
FWHM	-	Full Width at Half Maximum
2D	-	2 Dimensional
3D	-	3 Dimensional
$\rho$	-	Electrical Resistivity
$\sigma$	-	Electrical Conductivity
$d$	-	Thickness
$f(R)$	-	Correction Factors
$K_B$	-	Boltzmann Constant = $8.6173 \times 10^{-5}$ eV K <sup>-1</sup>
T <sub>A</sub>	-	Annealing Temperature



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# CHAPTER 1

## INTRODUCTION

### 1.1 Background of Research

Thin film is defined as a coated layer of materials consisted of metal, semiconductor, and insulator with the thickness ranging from nanometer up to several micrometers in scale. In 1857, Michael Faraday invented the first metallic thin film via electrolysis process. Hence, the studied of the thin films has been attracted much more attention due to it's potentially for application in nano scale devices. The rapid growth in thin film technology leads to the new discoveries in science and technology and as the result, it was widely applied in engineering process system in most recent years. Moreover, thin films have the low power consumption, small occupying spaces and high speed performance.

Among the materials, zinc oxide compound semiconductor contributing a significant development in thin films technology. The hexagonal wurtzitic zinc oxide (ZnO) has a wide direct band gap of 3.37 eV and exciton binding energy of 60 meV at room temperature which three times larger than that of GaN (20 meV) [1-4]. ZnO is an intentional n-type semiconductor which resulted from active native stoichiometric points defects such as vacancies, interstitials and antisites [4]. Furthermore, ZnO have the excellent properties of non-toxicity, hydrogen and plasma stability and high transparency in visible region [5]. Hence, ZnO thin films becoming the promising material in fabricating various electronic devices such as gas sensor [6], optoelectronics [7], transparent electrode in solar cell panel [8] and light emitting diode (LED) [9].

## 1.2 Problem Statement

Previously, there are a numbers of researchers reported on the sol-gel ZnO thin films prepared under the dip coating and spin coating deposition technique. As the example, Yi Chen *et al.* [10] prepared the ZnO thin films via the sol-gel spin coating technique onto the silicon substrate and studied the effect of annealing temperature on the ZnO films characteristics with the temperature range from 550 to 950 °C. Meanwhile, Sivakumar K. *et al.* [11] and Kyu Seog Hwang *et al.* [12] also reported the influence of annealing temperature prior to the nanocrystallinity of ZnO thin films fabricated via the sol-gel dip coating and spin coating method onto the glass substrate respectively. In Sivakumar K. *et al.* [11] work, they varied the annealing temperatures only as 300, 400, and 500 °C and Kyu Seog Hwang *et al.* [12] varied the annealing temperatures from 100 to 500 °C with every 100 °C increment step. Moreover, Jianguo *et al.* [13] studied the effect of precursor solution concentration which varied from 0.02 to 0.08 M on the structural and photoluminescence properties of sol-gel spin coating derived ZnO thin films. In our research work, the ZnO thin films were also prepared by the low cost sol-gel dip coating method with the varied parameters of annealing temperature and the level of precursor solution concentration. The sol-gel ZnO thin films were only prepared under the conditions of low annealing temperature together with low Zn<sup>2+</sup> precursor solution concentration. Therefore, the influence of these deposition parameters and the relationship within structural and electrical conductivity measurement of sol-gel ZnO films have been studied in detail.

### 1.3 Research Objectives

The objectives of this research are:

- i) To synthesize the ZnO thin films via the sol-gel dip coating method.
- ii) To determine the effect of annealing temperature and precursor solution concentration onto the structural properties and electrical conductivity of ZnO films.
- iii) To develop the Van der Pauw electrical resistivity measurement system.
- iv) To determine the relationship within structural and electrical conductivity of sol-gel ZnO films.

### 1.4 Scope of Research

The scopes of this research included the preparation of ZnO thin films via the sol-gel dip coating deposition method with varied the annealing temperature and the level of precursor solution concentration. In the of sol-gel dip coated ZnO films process, the withdrawal speed and preheating temperature were fixed at 10 mm/min and 200 °C respectively. Meanwhile, the coating cycle from withdrawal to preheating step was fixed at nine cycles in the entire ZnO films preparation work. The annealing temperatures varied from 350 to 550 °C with the increment step of 50 °C which considered as low annealing temperature range. The Zn<sup>2+</sup> solution concentration varied from 0.10 to 0.30 M with 0.05 M increment step. The structural properties of the sol-gel ZnO films were studied by using X-ray Diffractometer (XRD), atomic force microscope (AFM) and the Energy Dispersive Analysis of X-Ray (EDX). The thickness of the prepared sol-gel ZnO films was determined by the surface profilometer. Meanwhile, the Van der Pauw resistivity measurement method was used to determine the electrical conductivity of sol-gel ZnO films. Thus, the possible relationship of the structural and electrical conductivity of sol-gel prepared ZnO films been reported.

## **1.5 Significant of the Research**

In this research work, the undoped ZnO films prepared by sol-gel dip coating deposition method due to its simplicity in controlling the films compositional, ability to fabricate a large scale area of thin film, low costing consumption and high films homogeneity. The study with respect to the effect of annealing temperature and precursor solution concentration on the structural properties and electrical conductivity level of ZnO films has been conducted. This research work outcomes can be a part of fundamental platform for the synthesis of novel ZnO nanostructured materials such as nanorods (1D), nanowires (1D) and nanoflower (3D) in future.

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